



Corres. and Mail  
**BOX AF**

41

AF/2800

Response After Final Rejection  
Group Art Unit 2879, Expedited Procedure

03500.013314.2

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

TOSHIKAZU ONISHI, ET AL.

Application No.: 10/014,131

Filed: December 13, 2001

For: METHOD FOR  
MANUFACTURING ELECTRON  
EMISSION ELEMENT,  
ELECTRON SOURCE, AND  
IMAGE FORMING APPARATUS

) Examiner: K. Ramsey

) Group Art Unit: 2879

) September 30, 2003

RECEIVED  
OCT - 8 2003  
TECHNOLOGY CENTER 2800

Mail Stop AF  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

REQUEST FOR RECONSIDERATION AFTER FINAL REJECTION

Sir:

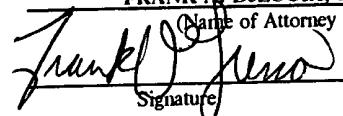
This Request For Reconsideration is filed in response to the Office Action (Paper No. 7) of June 30, 2003. Applicants submit the following comments in response to the Office Action.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on September 30, 2003.

(Date of Deposit)

FRANK A. DeLUCIA, JR. (REG. #42,476)

(Name of Attorney for Applicant)



September 30, 2003

Signature

Date of Signature